

	Application No.	oplication No. Applicant(s)	
Notice of Allowability	09/759,362	AOAI ET AL.	
	Examiner	Art Unit	
	John S. Chu	1752	
The MAILING DATE of this communication appe All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate commed GHTS. This application is	in this application. If not include the include the include the include the include in the include include in the include include in the include include in the include	ded e.course THIS
1. This communication is responsive to <u>2/23/04</u> .			
2. The allowed claim(s) is/are 1,6-9 and 11-17.			
3. The drawings filed on are accepted by the Examinet	r.		
 Acknowledgment is made of a claim for foreign priority una)	been received. been received in Application cuments have been receive	on No ed in this national stage applic	
5. A SUBSTITUTE OATH OR DECLARATION must be submi INFORMAL PATENT APPLICATION (PTO-152) which give	tted. Note the attached EX s reason(s) why the oath o	AMINER'S AMENDMENT or l	NOTICE OF
 CORRECTED DRAWINGS (as "replacement sheets") mus (a) ☐ including changes required by the Notice of Draftsperson 1) ☐ hereto or 2) ☐ to Paper No./Mail Date (b) ☐ including changes required by the attached Examiner's Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the deposition of the deposition of the properties of	on's Patent Drawing Review 5 Amendment / Comment on the 84(c)) should be written on the 10 header according to 37 CI	r in the Office action of the drawings in the front (not th FR 1.121(d).	·
attached Examiner's comment regarding REQUIREMENT F	OR THE DEPOSIT OF BIG	DLOGICAL MATERIAL.	note the
Attachment(s) 1. ☐ Notice of References Cited (PTO-892)	5 Notice of Ir	starmal Datant Application (DT	50.450)
2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)		nformal Patent Application (PT summary (PTO-413),	O-152)
3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/08 Paper No./Mail Date	Paper No B), 7. ☐ Examiner's	/Mail Date Amendment/Comment	
 Examiner's Comment Regarding Requirement for Deposit of Biological Material 		Statement of Reasons for Alle	owance
c. Disagradi material	9.		

Application/Control Number: 09/759,362

Art Unit: 1752

REASONS FOR ALLOWANCE

The following is an examiner's statement of reasons for allowance: The claimed invention is drawn to the following:

1 (amended). A negative-working resist composition for electron beams or X-rays comprising (A) a compound generating an acid and/or radical species by the irradiation of electron beams or X-rays selected from the groups consisting of a

Art Unit: 1752

sulfonate compound of sulfonium, a sulfonate compound of iodonium, a sulfonic acid ester compound of N-hydroxyimide and a disulfonyldiazomethane compound, (B) a resin which is insoluble in water and soluble in an alkali aqueous solution and having a repeating unit shown by the following formula (a), (C) a crosslinking agent causing crosslinking with the resin of component (B) by the action of an acid, [and] (D) a compound having at least one unsaturated bond capable of being polymerized by an acid and/or a radical and (E) an organic basic compound,

$$-CH_2-C-$$

$$R_3$$

$$R_3$$

$$(OR_3)_3$$

wherein R₁ represents a hydrogen atom, a halogen atom, a cyano group, or an alkyl or haloalkyl group which may have a substituent; R₂ represents a hydrogen atom, or an alkyl, cycloalkyl, aryl, aralkyl, or acyl group which may have a substituent; R₃ and R₄, which may be the same or different, each represents a hydrogen atom, a halogen atom, a cyano group, or an alkyl, cycloalkyl, alkenyl, aralkyl, or aryl group which may have a substituent; A represents a single bond, or a divalent alkylene, alkenylene, cycloalkylene, or arylene group which may have a substituent, or -O-, -SO₂-, -O-CO-R₅-, -CO-O-R₆-, or -CO-N(R₇)-R₈-; R₅, R₆, and R₈, which may be the

Application/Control Number: 09/759,362

Art Unit: 1752

same or different, each represents a single bond, or an alkylene, alkenylene, cycloalkylene, or arylene group, which may have a substituent, singly or a divalent group formed by combining the above-described group and at least one kind selected from an ether structure, an ester structure, an amide structure, a urethane structure, and a ureido structure; R₁ represents a hydrogen atom, or an alkyl, cycloalkyl, aralkyl, or aryl group which may have a substituent; and n represents an integer of from 1 to 3; provided that plural R₂s, or R₂ and R₃ or R₄ may combine with each other to form a ring.

Claim 9 recites a negative resist composition comprising an acid or radical generating compound, a crosslinking agent and a resin which has an unsaturated bond. Claim 9 was indicated to be allowable over the prior art of record as seen in the Office action mailed October 22, 2003, paragraph 5 and is included by reference

The claimed composition in claim 1 recites a particular combination of ingredients (A)(D) in a negative-working resist composition. The closest prior art and most recent prior art
reference to IMAI et al discloses, first a positive resist composition and second in the disclosure
suggests additive components, such as epoxy resins which can act as crosslinking agents. The
primary distinction as seen by the Office and why the claimed invention is not anticipated or
rendered obvious over IMAI et al is the weight that is given to the preamble. The preamble
states that the composition is a negative working composition meaning that the portions of the
resist composition that are exposed to light remain after development by a suitable developer,
while the prior art reference to IMAI et al recites a positive working composition which means
that the portions of the resist that are exposed to light are removed upon development by a
suitable developer.

Art Unit: 1752

For the reasons stated above claims 1, 6-9 and 11-17 are seen as allowable over the prior art of record and these claims are passed to issue.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Chu whose telephone number is (571) 272-1329. The examiner can normally be reached on Monday - Friday from 9:30 am to 6:00 pm.

The fax phone number for the USPTO is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (571) 272-1700.

John S. Chu

Primary Examiner, Group 1700

J.Chu May 16, 2004